

L1      CAS/STN FILE 'REGISTRY' ENTERED AT 07:15:30 ON 20 JUL 2005  
 L1      1 S SILICON/CN

L2      FILE 'HCAPLUS' ENTERED AT 07:16:53 ON 20 JUL 2005  
 L2      3972 S L1(L) (NANOPARTIC? OR NANOSPHER? OR  
           NANOGRA? OR NANOSIZ? OR NANOPELLET? OR NANOPULVER? OR NANOPOWDE  
           R? OR POWDER? OR PULVER?)

L3      FILE 'HCAPLUS' ENTERED AT 07:17:10 ON 20 JUL 2005  
 L3      309 S L1(L)GRANUL?  
           E NANOPARTICLES/CT  
           E E3+ALL/CT

L4      1019 S NANOPARTICLES/CT(L) (SI OR SILICON)

L5      1412 S NANOCRYSTALS/CT(L) (SI OR SILICON)  
           E LUMINESCENCE/CT  
           E E3+ALL/CT

L6      234371 S (LUMINESCENCE/CT OR "LUMINESCENCE (L)  
           IR-INDUCED"/CT OR "STOKES' LAW"/CT OR "IR-INDUCED LUMINESCENCE"  
           /CT OR "IR-STIMULATED LUMINESCENCE"/CT OR "ISOTHERMAL LUMINESCE  
           NCE"/CT OR "LUMINESCENCE SPECTRA"/CT OR "PERSONOV EFFECT"/CT  
           OR PHOTOLUMINESCENCE/CT OR "SHPOL'SKII EFFECT"/CT OR "SORET  
           BANDS"/CT OR "SORET SPECTRAL BANDS"/CT OR "STIMULATED LUMINESCE  
           NCE"/CT OR "STIMULATED LUMINESCENT EMISSION"/CT OR "VAVILOV'S  
           LAW"/CT OR CATHODOLUMINESCENCE/CT OR "EXCITON LUMINESCENCE"/CT  
           OR "LUMINESCENCE (L) EXCITON-PHONON"/CT OR "LUMINESCENCE (L)  
           MAGNETO-, EXCITON"/CT OR "LUMINESCENCE (L) RECOMBINATION,  
           EXCITON"/CT OR "LUMINESCENCE, ELECTRO- (L) EXCITON"/CT OR  
           "MAGNETOOPTICAL EFFECT (L) LUMINESCENCE"/CT OR FLUORESCENCE/CT  
           OR "EXCIMER FLUORESCENCE"/CT OR "LASER INDUCED FLUORESCENCE"/CT  
           OR "FLUORESCENCE (L) EXCITATION, LASER-INDUCED"/CT OR  
           "FLUORESCENCE (L) TWO-PHOTON"/CT OR "POLARIZED FLUORESCENCE"/CT  
           OR "RESONANCE FLUORESCENCE"/CT OR SUPERFLUORESCENCE/CT OR  
           "X-RAY (L) FLUORESCENCE"/CT OR "X-RAY FLUORESCENCE"/CT OR  
           "X-RAY SPECTRA (L) FLUORESCENCE"/CT OR "IR LUMINESCENCE"/CT OR  
           "INFRARED LUMINESCENCE (L) CHEMILUMINESCENCE"/CT OR "INFRARED  
           LUMINESCENCE (L) NEAR-IR"/CT OR "LUMINESCENCE (L) NEAR-IR"/CT  
           OR "LUMINESCENCE, CHEMI- (L) IR"/CT OR "LUMINESCENCE, BIO-"/CT  
           OR "LUMINESCENCE, BIOLUMINESCENCE"/CT OR "LUMINESCENCE, BIO-  
           (L) ULTRaweak"/CT OR "LUMINESCENCE, CATHODO-"/CT OR "LUMINESCEN  
           CE, CHEMI-"/CT OR "LUMINESCENCE, CHEMILUMINESCENCE"/CT OR  
           "LUMINESCENCE, CHEMI- (L) ELECTROCHEMI-"/CT OR "LUMINESCENCE,  
           ELECTRO-"/CT OR "LUMINESCENCE, ELECTROLUMINESCENCE"/CT OR  
           "GUDDEN-POHL EFFECT"/CT OR "LUMINESCENCE, ELECTRO- (L)  
           BLUE"/CT OR "LUMINESCENCE, RADIO-"/CT OR "LUMINESCENCE,  
           THERMO-"/CT OR MAGNETOLUMINESCENCE/CT OR "LUMINESCENCE (L)  
           MAGNETO-, EXCITON"/CT OR "MAGNETOOPTICAL EFFECT (L) LUMINESCENC  
           E"/CT OR "MAGNETOOPTICAL EFFECT (L) LUMINESCENCE"/CT OR  
           "OPTICAL NONLINEAR PROPERTY (L) LUMINESCENCE"/CT OR PHOSPHORESC  
           ENCE/CT OR "PIEZOOPTICAL PROPERTY (L) PIEZOLUMINESCENCE"/CT OR  
           "POLARIZED LUMINESCENCE"/CT OR "L  
 L7      701 S "PHOTON EMISSION"/CT  
 L8      5981 S "LUMINESCENT SUBSTANCES"/CT  
 L9      3245 S SCINTILLATION/CT  
 L10     54248 S PHOTOLUM?  
 L11     16177 S (PHOTO##### OR LIGHT OR IRRADIAT#### OR  
           RADIAT#####) (3A) LUMINESC##### OR  
 L12     1639 S (SI OR SILICON) (3A) (NANOSPHER? OR NANOGRA  
           NU L? OR NANOPELLET? OR NANOPARTIC?)  
 L13     1080 S ((L2 OR L3 OR L4 OR L5) OR L12) AND (L6 OR  
           L7 OR L8 OR L9 OR L10 OR L11)  
 L14     805 S (LUMINESCENT SUBSTANCES OR PHOTOLUM? OR  
           LUMINESC##### (L) PHOTO) AND L13

L15        410 S L13 AND (HEAT##### OR VCSEL OR LASER OR  
LASED OR LASING OR LASER OR RADIAT##### OR IRRADIAT#####)  
L16        1 S US2004229447/PN  
L17        SEL PLU=ON L16 1- NCL IC :        2 TERMS  
L18        8988 S L17  
L19        4 S L12 AND L18  
L20        121 S L12 AND PRECURSOR  
L21        SEL PLU=ON L16 1- RN :        13 TERMS  
L22        1 S L13 AND L18  
L23        1019444 S L21  
L24        978 S L13 AND L23  
L25        0 S L22 NOT L16  
L26        3 S L19 NOT L16  
L27        3 S L23 AND L26  
            D ALL HITSTR TOT

FILE 'STNGUIDE' ENTERED AT 07:37:04 ON 20 JUL 2005

FILE 'HCAPLUS' ENTERED AT 07:38:49 ON 20 JUL 2005

L28        2 S L13 AND (SHEATH OR REACTANT) (2A) (GAS OR H2  
OR H OR HYDROGEN)  
L29        9 S L13 AND (WET OR ACID####) (3A) ETCH####

FILE 'REGISTRY' ENTERED AT 07:38:51 ON 20 JUL 2005

L30        34 S H4SI/MF  
L31        163981 S SILANE  
L32        31 S (HELIUM OR NITROGEN OR ARGON)/CN OR N2/MF  
L33        1697 S CARBON DIOXIDE OR CO2/MF  
L34        20 S (F6S OR F4SI)/MF  
L35        257 S CELLULOSE NITRATE  
L36        35 S FH/MF OR HNO3/MF  
L37        1 S METHANOL/CN  
L38        1 S ISOPROPANOL/CN  
L39        1 S WATER/CN  
L40        1 S HYDROXYL/CN  
L41        10 S HOSI/MF

FILE 'HCAPLUS' ENTERED AT 07:42:04 ON 20 JUL 2005

L42        35 S L13 AND L30  
L43        77 S L13 AND L31  
L44        92 S L13 AND ?SILANE?  
L45        3 S L13 AND HYDROSILYL?  
L46        3 S L13 AND SILANI?  
L47        30 S L13 AND (STABILIS? OR STABILIZ?)  
L48        56 S L13 AND SURFACE(3A) (OXID#### OR OXIDI? OR  
OXIDAT?)  
L49        28 S L13 AND (CO2 OR CARBON DIOXIDE OR C  
DIOXIDE OR L33)  
L50        54 S L13 AND (INERT OR NOBLE OR N2 OR HE OR  
HELIUM OR AR OR ARGON) (3A) GAS  
L51        84 S L13 AND L32  
L52        6 S L13 AND L34  
L53        1 S L13 AND L35  
L54        37 S L13 AND L36  
L55        8 S L13 AND L37  
L56        2 S L13 AND L38  
L57        9 S L13 AND L39  
L58        0 S L13 AND L40  
L59        0 S L13 AND L41  
L60        15 S L13 AND (OH OR SIOH OR HYDROXY####)  
L61        32 S L13 AND SURFACE(5A) (TERMINA##### OR  
FRAGMENT##### OR SUBSTITUENT OR FUNCTIONAL##### OR GROUPS)

L62        0 S L13 AND RTO  
 L63        44 S L13 AND DECOMP?  
 L64        244 S L13 AND (THERMAL? OR HEAT##### OR RTA OR  
              RTP)  
 L65        85 S L13 AND TREAT#####  
 L66        107 S L13 AND CONDITION  
 L67        2 S L13 AND REACTANT  
              S L13 AND HYDROGEN/CN

FILE 'REGISTRY' ENTERED AT 07:50:05 ON 20 JUL 2005  
 L68        1 S HYDROGEN/CN

FILE 'HCAPLUS' ENTERED AT 07:50:05 ON 20 JUL 2005  
 L69        300553 S L68  
 L70        62 S L13 AND L69  
 L71        71 S L13 AND VISIBLE SPECTRUM  
 L72        32 S L13 AND PEAK#####(3A)(EMIT##### OR  
              EMISS#####)  
 L73        26 S L13 AND (CO2 OR DIOXIDE)(3A)LASER  
 L74        0 S L13 AND L33(L)(LASER OR LASED OR LASING)  
 L75        11 S L13 AND (WASH##### OR CLEAN##### OR RINS#####)

L76        9 S L13 AND (FILTER? OR FILTR#####)  
 L77        0 S L13 AND CELLULOSE  
 L78        35 S L13 AND PRECURSOR  
 L79        82 S (L10 OR L11 OR L12 OR L13 OR L14 OR L15)  
              AND (CELLULOSE OR L35)  
 L\*\*\* DEL 341 S L10-15 AND (ORANGE OR READ)(4A)(LIGHT OR EMIT##### OR EMISS##  
 L80        345 S (L10 OR L11 OR L12 OR L13 OR L14 OR L15)  
              AND (ORANGE OR READ)(4A)(LIGHT OR EMIT##### OR EMISS##### OR  
              PEAK OR WAVELENGTH OR LAMBDA OR FREQUENCY OR COLOR?)  
 L81        10 S L13 AND L80  
 L82        34 S L13 AND BRIGHT#####  
 L83        92 S L13 AND (ISOLATED OR SINGLE OR INDIVIDUAL##  
              # OR SEPARAT##### OR EACH)(3A)(NANOPARTICLE OR SI OR SILICON)  
 L84        309 S L13 AND SURFACE  
 L85        158 S L13 AND (HYDROGEN OR H2 OR H(3A)GAS)  
 L86        69 S (L28 OR L29) OR (L45 OR L46) OR (L52 OR  
              L53) OR (L55 OR L56 OR L57) OR L60 OR L67 OR (L75 OR L76) OR  
              L81  
 L87        69 S L86 NOT L26  
 L88        49 S L87 AND NANOPARTIC?  
 L89        50 S L87 AND PHOTOLUM?  
 L90        34 S L88 AND L89  
              D ALL HITSTR TOT  
 L91        1184 S (L42 OR L43 OR L44 OR L45 OR L46 OR L47 OR  
              L48 OR L49 OR L50 OR L51 OR L52 OR L53 OR L54 OR L55 OR L56 OR  
              L57 OR L58 OR L59 OR L60 OR L61 OR L62 OR L63 OR L64 OR L65 OR  
              L66 OR L67) OR (L70 OR L71 OR L72 OR L73 OR L74 OR L75 OR L76  
              OR L77 OR L78 OR L79 OR L80 OR L81 OR L82 OR L83 OR L84 OR L85  
              OR L86 OR L87 OR L88 OR L89)  
 L92        1150 S L91 NOT (L26 OR L90)  
 L93        6 S L92 AND LUMINESCENT MATERIALS  
              D ALL HITSTR TOT  
 L94        576 S L92 AND ?LUMINESC?(5A)(NANOS? OR NANOC? OR  
              MESOP? OR NANOG? OR NANOP?)  
 L95        704 S L92 AND (SI OR SILICON)(5A)(NANOS? OR  
              NANOC? OR MESOP? OR NANOG? OR NANOP?)  
 L96        642 S L92 AND (SI OR SILICON)(5A)?LUMINESC?  
 L97        547 S L94 AND L95  
 L98        518 S L97 AND L96  
 L99        105 S L98 AND (OXIDI? OR OXIDAT?)

L100        32 S L98 AND STABILI?  
 L101        26 S L98 AND DECOMP?  
 L102        138 S L98 AND THERMAL?  
 L103        31 S L98 AND HEAT?  
 L104        2 S L98 AND ?SILYL?  
 L105        0 S L98 AND ?SILANI?  
 L106        0 S L98 AND SIOH  
 L107        0 S L98 AND OH  
 L108        3 S L98 AND HYDROX#####  
 L109        17 S L98 AND ACID#####  
 L110        43 S L98 AND ETCH#####  
 L111        132 S L98 AND LASER  
 L112        0 S L98 AND SHEATH  
 L113        27 S L98 AND BRIGHT#####  
 L114        119 S (L94 OR L95 OR L96 OR L97 OR L98) AND  
               ((L100 OR L101) OR (L104 OR L105 OR L106 OR L107 OR L108 OR  
               L109 OR L110) OR L113)  
 L115        4 S L114 AND L99 AND (L102 OR L103) AND L111  
 L116        33 S L114 AND L111  
 L117        21 S L116 AND (L99 OR L102 OR L103)  
 L118        26 S (L104 OR L105 OR L106 OR L107 OR L108) OR  
               L115 OR L117  
 D ALL HITSTR TOT  
 S (L30 OR L32-41 OR H2/MF) AND L98

FILE 'REGISTRY' ENTERED AT 08:10:24 ON 20 JUL 2005

L119        19 S H2/MF

FILE 'HCAPLUS' ENTERED AT 08:10:24 ON 20 JUL 2005

L120        365106 S L119  
 L121        136 S (L30 OR (L32 OR L33 OR L34 OR L35 OR L36  
               OR L37 OR L38 OR L39 OR L40 OR L41) OR L120 ) AND L98  
 L122        120 S L121 NOT (L118 OR L26 OR L90 OR L93)  
 L123        112 S L122 AND ?LUMINESC?(3A)(SI OR SILICON OR  
               POLYSILICON)  
               S L122 AND SILICON/CN

FILE 'REGISTRY' ENTERED AT 08:12:06 ON 20 JUL 2005

L124        1 S SILICON/CN

FILE 'HCAPLUS' ENTERED AT 08:12:06 ON 20 JUL 2005

L125        416381 S L124  
 L126        114 S L122 AND L125  
 L127        9 S L122 AND STABILI?  
 L128        26 S L122 AND (OXIDI? OR OXIDAT?)  
 L129        3 S L122 AND DECOMP?  
 L130        0 S L122 AND (?SILANI? OR ?SILYL?)  
 L131        18 S L122 AND (SIH4 OR ?SILANE?)  
 L132        4 S L128 AND L131  
 L133        27 S L127 OR L129 OR L131 OR L132

## L133 ANSWER 18 OF 27 HCAPLUS COPYRIGHT ACS on STN

AN 1999:389792 HCAPLUS

DN 131:108498

ED Entered STN: 24 Jun 1999

TI Effects of hydrogen in the annealing environment on photoluminescence from Si nanoparticles in SiO<sub>2</sub>

AU Withrow, S. P.; White, C. W.; Meldrum, A.; Budai, J. D.; Hembree, D. M., Jr.; Barbour, J. C.

CS Oak Ridge National Laboratory, Oak Ridge, TN, 37831, USA

SO Journal of Applied Physics (1999), 86(1), 396-401

CODEN: JAPIAU; ISSN: 0021-8979

PB American Institute of Physics

AB The role of H in enhancing the photoluminescence (PL) yield observed from Si nanocrystals embedded in SiO<sub>2</sub> was studied. SiO<sub>2</sub> thermal oxides and bulk fused SiO<sub>2</sub> samples were implanted with Si and subsequently annealed in various ambients including H or D forming gases (Ar+4%H<sub>2</sub> or Ar+4%D<sub>2</sub>) or pure Ar. Results are presented for annealing at 200-1100°. Depth and concentration profiles of H and D at various stages of processing were measured using elastic recoil detection. H or D is observed in the bulk after annealing in forming gas but not after high temperature (1100°) anneals in Ar. The presence of H dramatically increases the broad PL band centered in the near IR after annealing at 1100° but has almost no effect on the PL spectral distribution. H is found to selectively trap in the region where Si nanocrystals are formed, consistent with a model of H passivating surface states at the Si/SiO<sub>2</sub> interface that leads to enhanced PL. The thermal stability of the trapped H and the PL yield observed after a high temperature anneal were studied. The H concentration and PL yield are unchanged for subsequent anneals up to 400°. However, >400° the PL decreases and a more complicated H chemical is evident. Similar concns. of H or D are trapped after annealing in H<sub>2</sub> or D<sub>2</sub> forming gas; however, no differences in the PL yield or spectral distribution are observed, indicating that the electronic transitions resulting in luminescence are not dependent on the mass of the H species.

IT Annealing

Luminescence

Nanoparticles

Thermal stability

(effects of hydrogen and deuterium in annealing environment on photoluminescence from Si nanoparticles in SiO<sub>2</sub>)

IT 7440-37-1, Argon, uses

(annealing in; effects of hydrogen and deuterium in annealing environment on photoluminescence from Si nanoparticles in SiO<sub>2</sub>)

IT 12385-13-6, Hydrogen(atomic), occurrence 16873-17-9,

Deuterium(atomic), occurrence

(effects of hydrogen and deuterium in annealing environment on photoluminescence from Si nanoparticles in SiO<sub>2</sub>)

IT 7440-37-1, Argon, uses

(annealing in; effects of hydrogen and deuterium in annealing environment on photoluminescence from Si nanoparticles in SiO<sub>2</sub>)

IT 1333-74-0, Hydrogen, processes 7782-39-0,

Deuterium, processes

(effects of hydrogen and deuterium in annealing environment on photoluminescence from Si nanoparticles in SiO<sub>2</sub>)

L118 ANSWER 17 OF 26 HCAPLUS COPYRIGHT ACS on STN

AN 2000:329679 HCAPLUS

ED Entered STN: 19 May 2000

TI Surface-chemical control of optical quenching processes at porous silicon interfaces: Generation of a stable-selective sulfur-dioxide sensor.

AU Bocarsly, Andrew B.; Wimbish, J. Clint

CS Department of Chemistry, Princeton University, Princeton, NJ, 08544, USA

SO Book of Abstracts, 219th ACS National Meeting, San Francisco, CA, March 26-30, 2000 (2000), COLL-414 Publisher: American Chemical Society, Washington, D. C..

CODEN: 69CLAC

DT Conference; Meeting Abstract

LA English

AB Visible photoluminescence from nanoscopic particles of silicon formed by anisotropic etching of single crystal silicon is a well-established phenomenon. A consensus appears to be forming that this process is associated with quantum confined states associated with the Si nanoparticles. Along with this conclusion, a variety of quenching mechanisms have been reported. Previously we indicated that static quenching via dangling bond surface states could be selected by the synthesis of a low quality ultrathin oxide layer on the porous silicon interface. We also demonstrated that such interfaces were selectively quenched by SO<sub>2</sub>(g). However, the tendency of the oxide interface to further develop in the presence of humid air made the observed quenching process unstable. We now report that, once formed, the Si/SiO<sub>x</sub> interface can be stabilized even in the presence of water at elevated temps. by modification with a silylfluorocarbon. This interface is permeable to sulfur dioxide allowing for continued quenching by this species over an extended time period, and making possible a functional sulfur dioxide sensor.

"/ X //

L90 ANSWER 22 OF 34 HCAPLUS COPYRIGHT ACS on STN

AN 2003:23721 HCAPLUS

DN 138:277780

ED Entered STN: 12 Jan 2003

TI Light-emitting silicon nanocrystals from laser pyrolysis

AU Huisken, Friedrich; Ledoux, Gilles; Guillois, Olivier; Reynaud, Cecile

CS Max-Planck-Institut fur Stromungsforschung, Gottingen, D-37073, Germany

SO Advanced Materials (Weinheim, Germany) (2002), 14(24), 1861-1865

CODEN: ADVMEW; ISSN: 0935-9648

PB Wiley-VCH Verlag GmbH &amp; Co. KGaA

DT Journal; General Review

LA English

CC 73-0 (Optical, Electron, and Mass Spectroscopy and Other Related Properties)

AB A review. Crystalline Si nanoparticles with diams. between 2.5 and 20 nm were prepared by CO<sub>2</sub>-laser-induced decomposition of silane in a gas flow reactor. A small portion of the products created in the reaction zone is extracted through a nozzle into a high-vacuum apparatus to form a freely propagating mol. beam of clusters and nanoparticles that can be deposited on suitable substrates. The strong visible photoluminescence (PL) of the Si nanocrystals was studied as a function of their size, and as a function of the time for which they are exposed to air. All observations can be explained from quantum confinement as the only origin of the PL. Chemical methods are exploited to modify the surface of the Si nanoparticles and to reduce their size, thus shifting their PL to shorter wavelengths. With this technique, the Si nanoparticles, collected in much larger quantities in the filter of the flow reactor, can be made strongly luminescent so that they may be used for various applications.

ST review luminescence silicon nanocrystal laser pyrolysis

IT Luminescence

Nanocrystals

Quantum size effect

        (light-emitting silicon nanocrystals from laser  
            pyrolysis)

IT Thermal decomposition

(photo-; light-emitting silicon nanocrystals from laser pyrolysis)

IT 7440-21-3, Silicon, properties

RL: PRP (Properties)

(light-emitting silicon nanocrystals from laser pyrolysis)

Micro-Raman

spectroscopy was used for characterization of the deposits  
(no data

given). Laser-driven nucleation in a flow reactor is a  
powerful technique

to produce fullerenes and Si quantum dots and other nano-  
size

semiconductors or high-temp. evapd. materials.

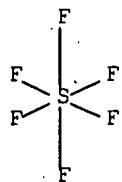
IT **2551-62-4, Sulfur hexafluoride**

(sensitizer for laser-induced gas phase synthesis of  
carbon

and silicon clusters)

RN 2551-62-4 HCPLUS

CN Sulfur fluoride (SF6), (OC-6-11)- (9CI) (CA INDEX NAME)



FILE 'REGISTRY' ENTERED AT 11:50:43 ON 20 JUL 2005

L1 20 S F6S/MF OR F4SI/MF

FILE 'HCPLUS' ENTERED AT 11:51:12 ON 20 JUL 2005

FILE 'HCPLUS' ENTERED AT 11:51:19 ON 20 JUL 2005

L2 162 S L1(L) (PHOTOSENSIT? OR SENSITIS? OR SENSITIZ?)

L3 0 S L2 AND PHOTOLUM?

L4 7 S L2 AND NANOPART?

L5 92 S L2 AND CO2 LASER

L6 2 S L4 AND L5

FILE 'SCISEARCH' ENTERED AT 11:53:49 ON 20 JUL 2005

E EHBREHT M, 1996/RE

FILE 'SCISEARCH' ENTERED AT 11:53:59 ON 20 JUL 2005

E EHBRECHT M, 1996/RE

L7 6 S E4-6 AND LASER?

L8 2 S L7 AND NANO#####

Jeff Harrison

Team Leader, STIC-EIC2800

JEF-4B68, 571-272-2511

L6 ANSWER 2 OF 2 HCPLUS COPYRIGHT ACS on STN

"10"

AN 1996:704301 HCPLUS

DN 126:24344

TI Deposition and analysis of carbon and **silicon clusters**  
generated by

**laser-induced gas phase reaction**

AU Ehbreht, M.; Ferkel, H.; Husken, F.; Holz, L.; Polivanov,  
Yu. N.; Smirnov,

V. V.; Stelmakh, O. M.

CS Max-Plank Institut fur Stromungsforschung, Goettingen,  
37073, Germany

SO Proceedings of SPIE-The International Society for Optical  
Engineering

(1996), 2778(Pt. 1, 17th Congress of the International  
Commission for

Optics, 1996, Pt. 1), 171-172

CODEN: PSISDG; ISSN: 0277-786X

PB SPIE-The International Society for Optical Engineering

DT Journal

LA English

AB Laser driven gas-phase synthesis in a flow reactor was  
employed for the

prodn. of C and Si cluster beams starting from gaseous  
compds. It is

based on a **CO<sub>2</sub>-laser**-induced decompr. of mol. gases

contg. C and Si, such as C<sub>2</sub>H<sub>2</sub> and **SiH<sub>4</sub>**. By introducing a  
skimmer into the

reaction zone, the generated clusters are transferred to  
the free mol.

flow and analyzed with a time-of-flight mass spectrometer.  
These clusters

were deposited on a Si or sapphire target at room temp.